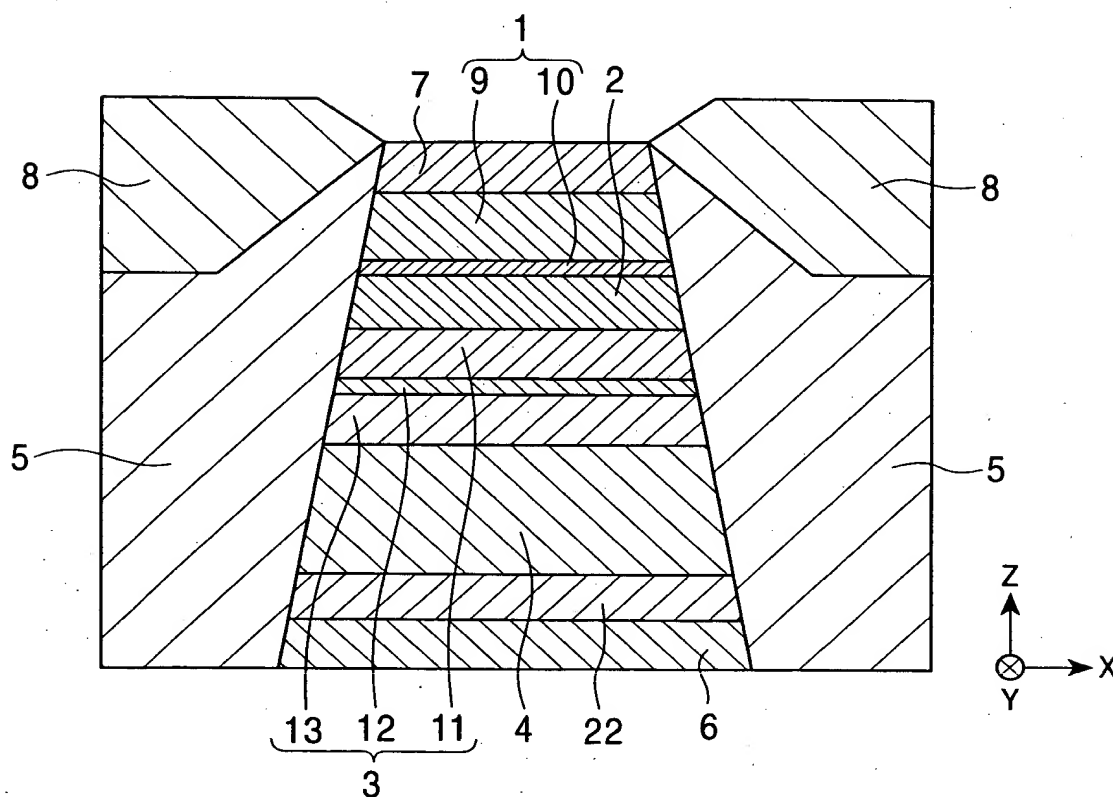


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FIG. 1



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FIG. 2

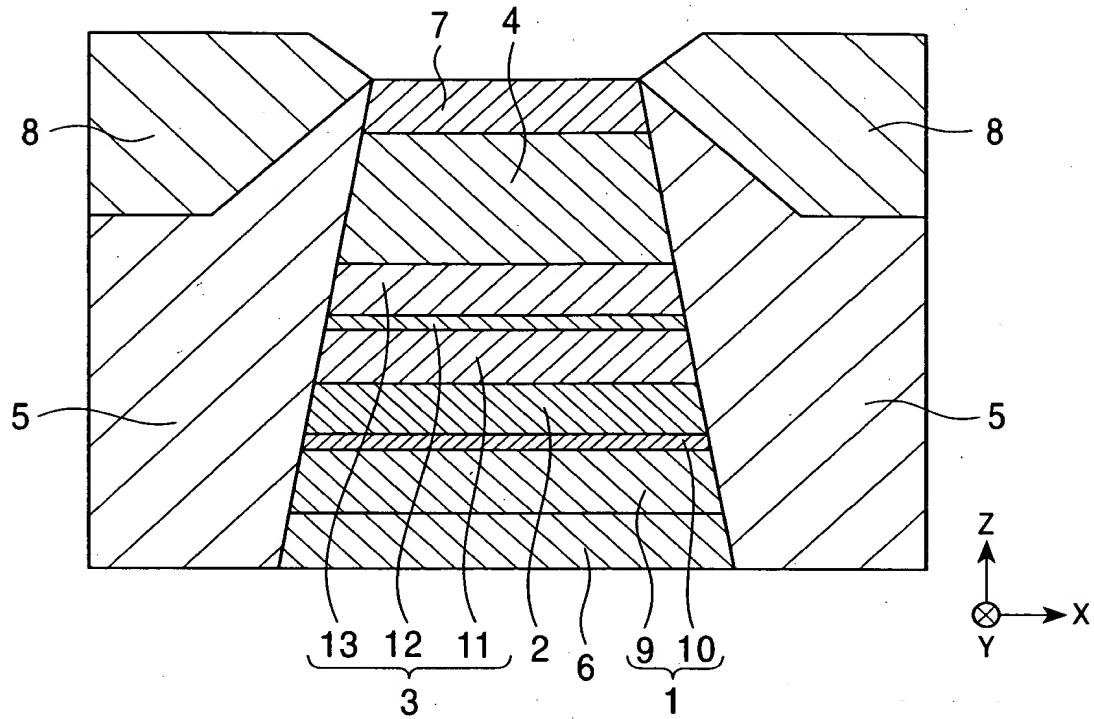
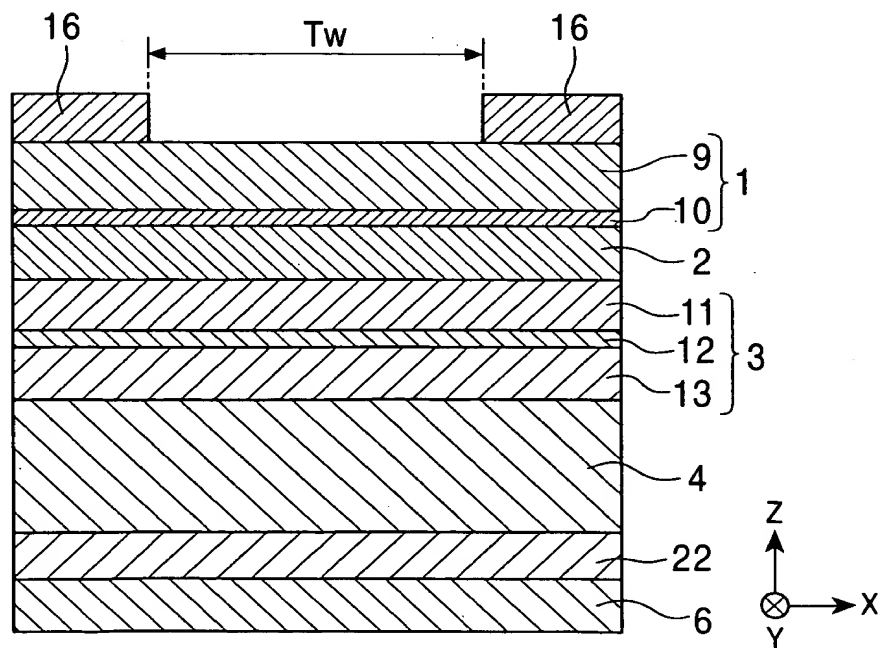
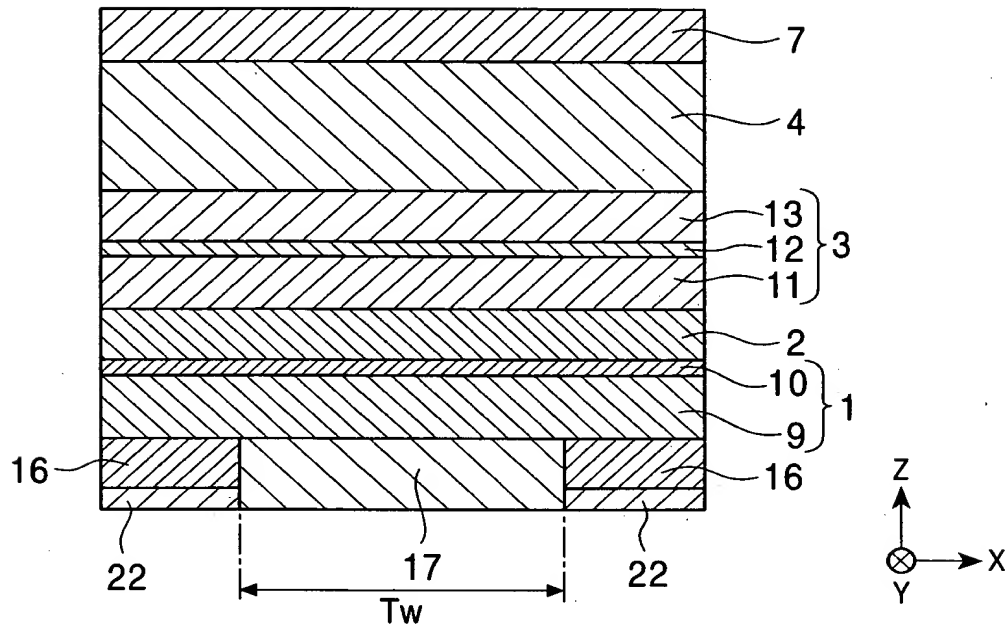


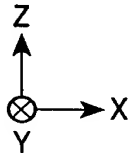
FIG. 3



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FIG. 4



[illegible]

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FIG. 6

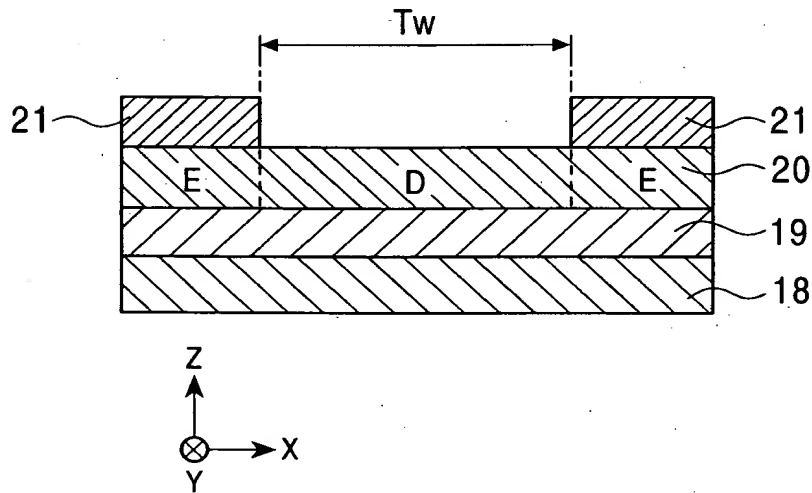
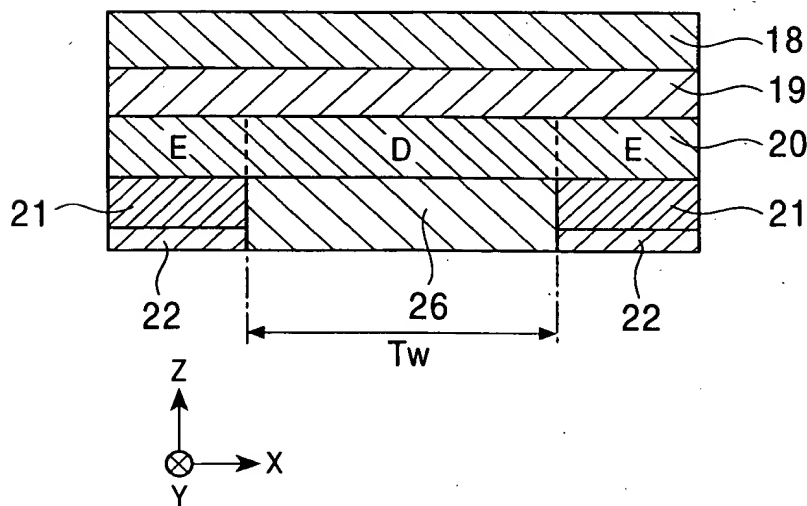
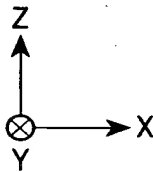
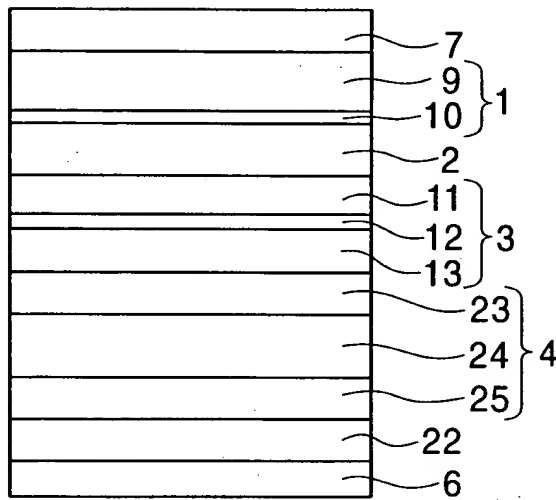


FIG. 7



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FIG. 8



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FIG. 9

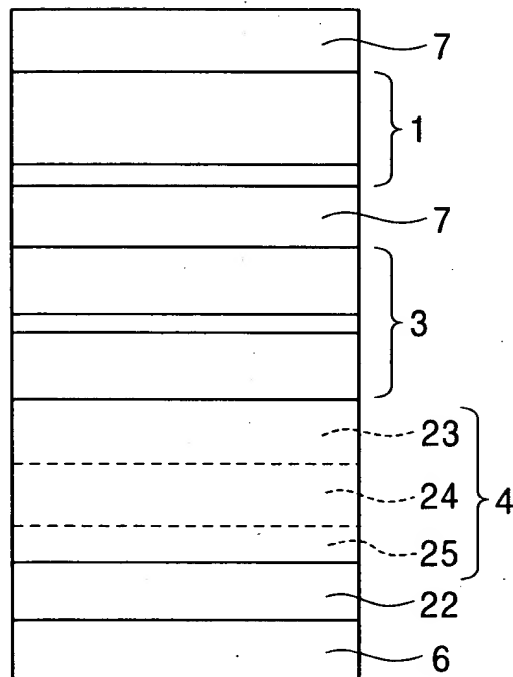
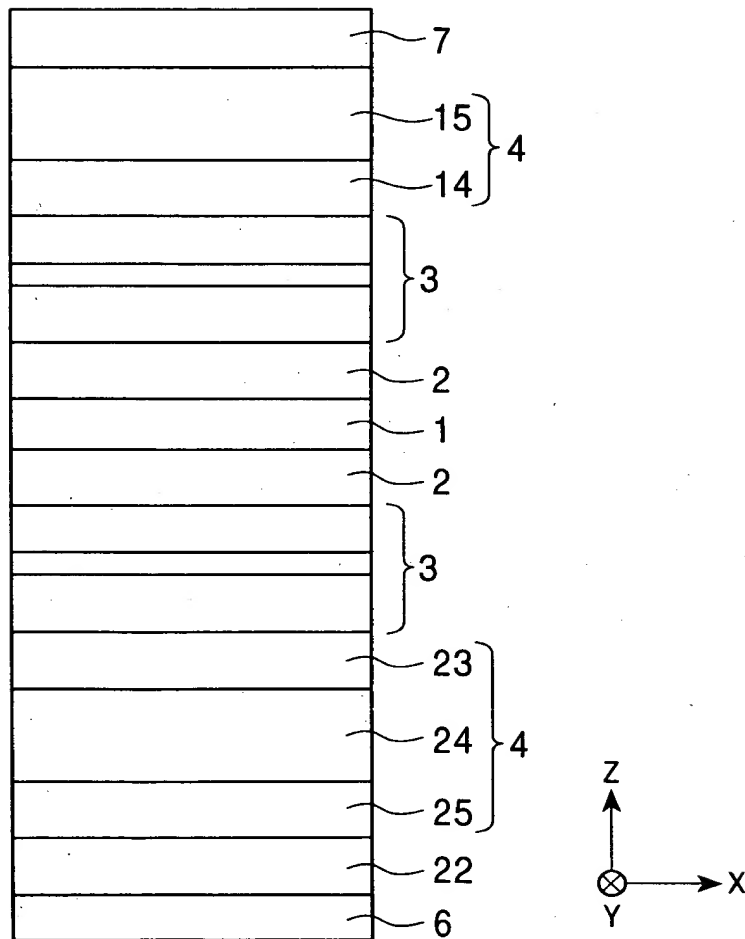


FIG. 9

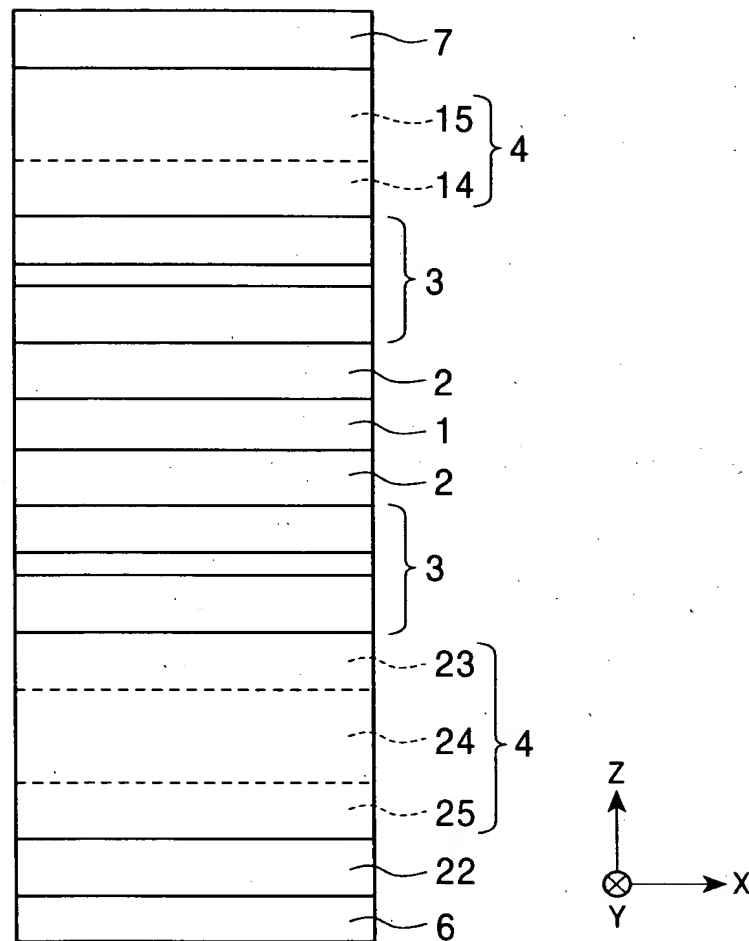
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FIG. 10



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FIG. 11



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FIG. 12

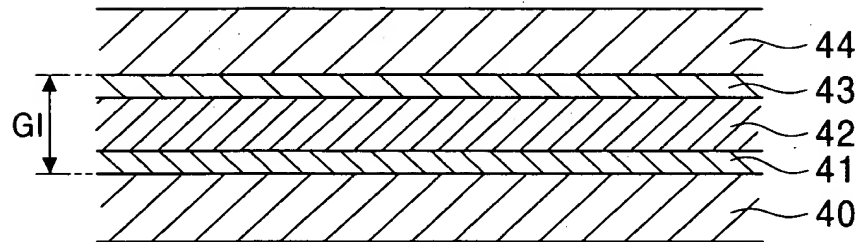
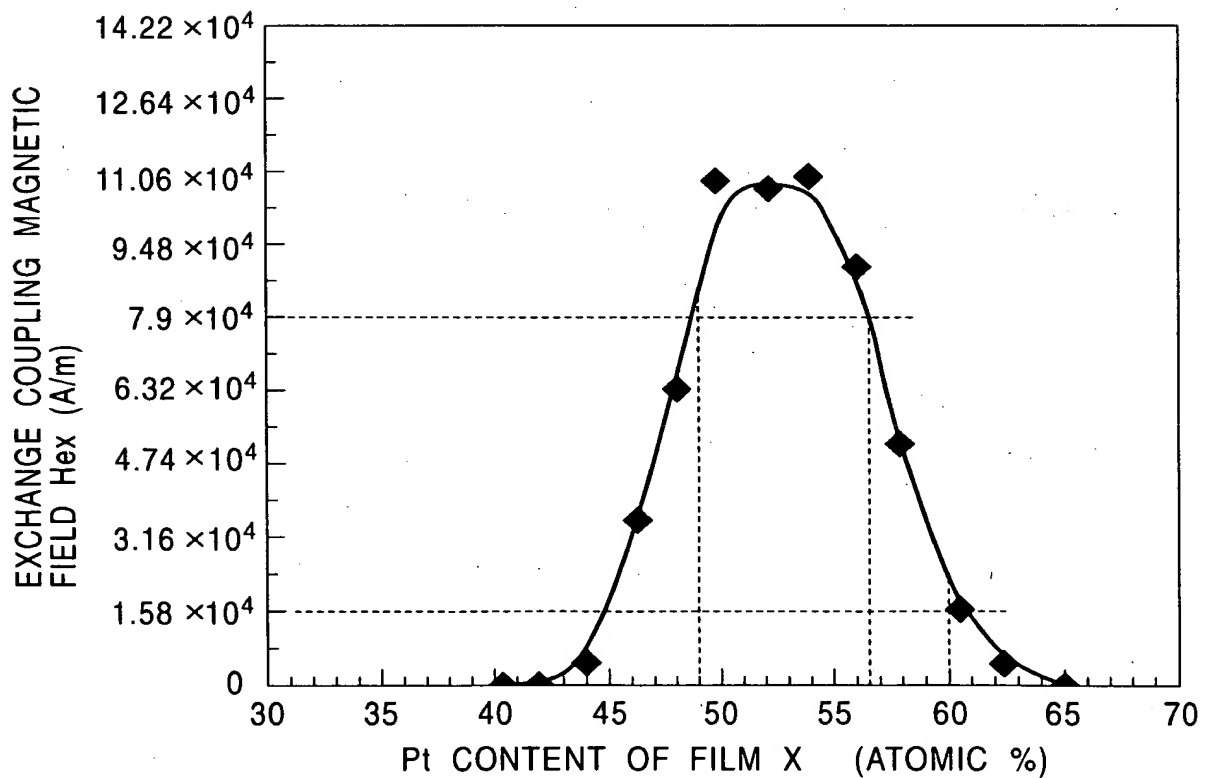


FIG. 13



FILM STRUCTURE: Si SUBSTRATE/ALUMINA/Ta(3nm)/NiFe
 (3nm)/PtMn(15nm)/Co
 (1.5nm)/Ru(0.8nm)/Co
 (2.5nm)/Cu(2.3nm)/Co
 (1nm)/NiFe(3nm)/Cu(1.5nm)/Ta(3nm)

FIG. 12

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FIG. 14

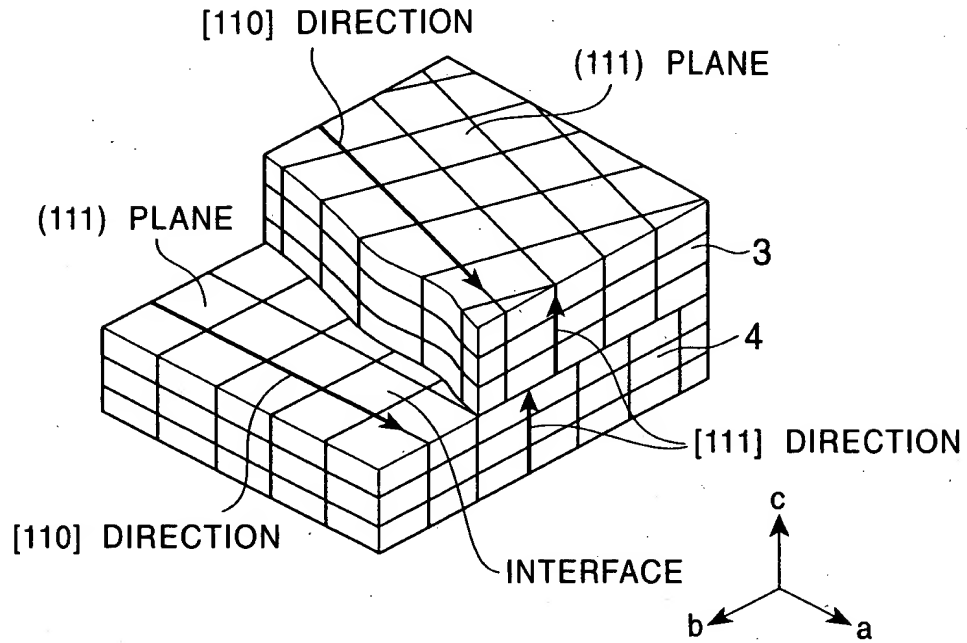
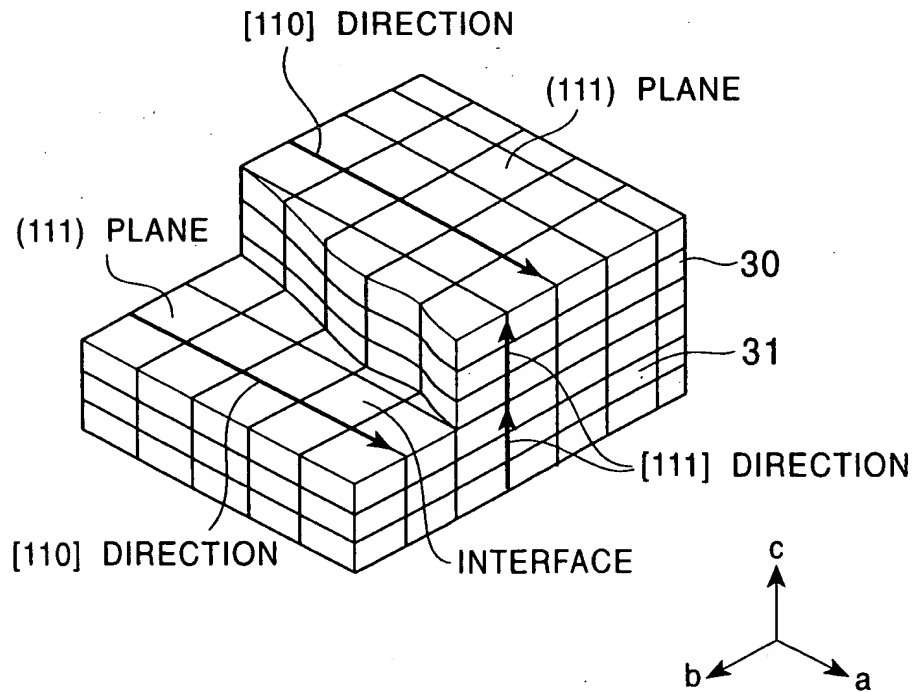


FIG. 15



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FIG. 16

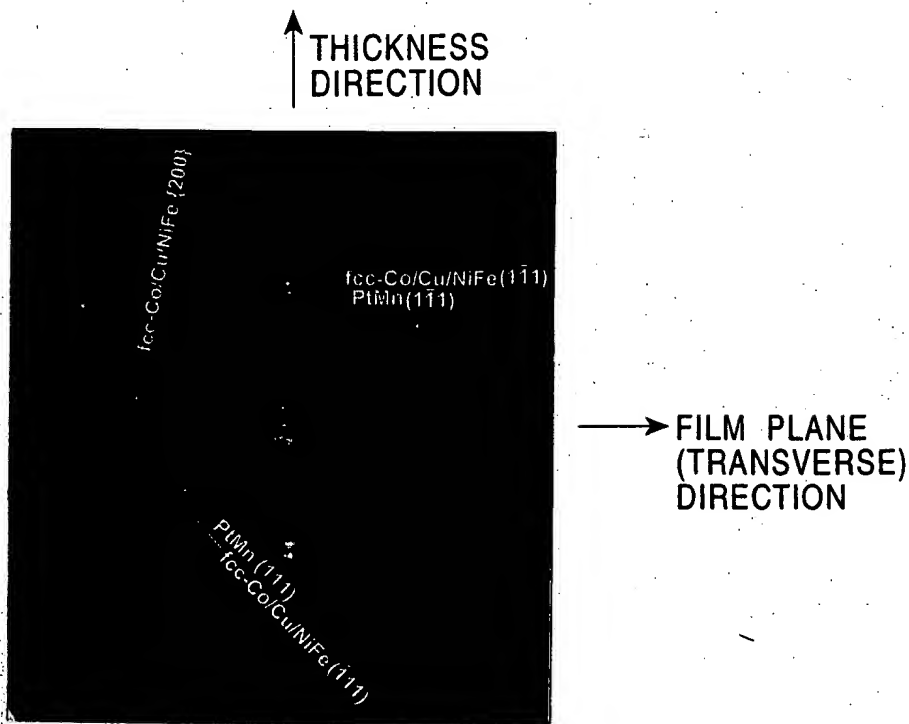
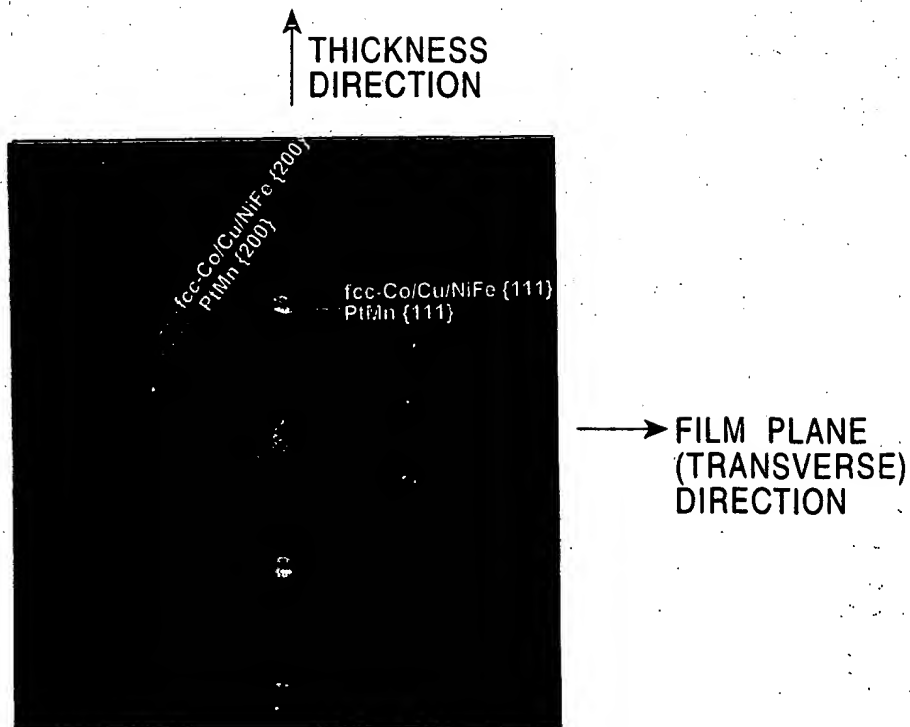


FIG. 17



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FIG. 18

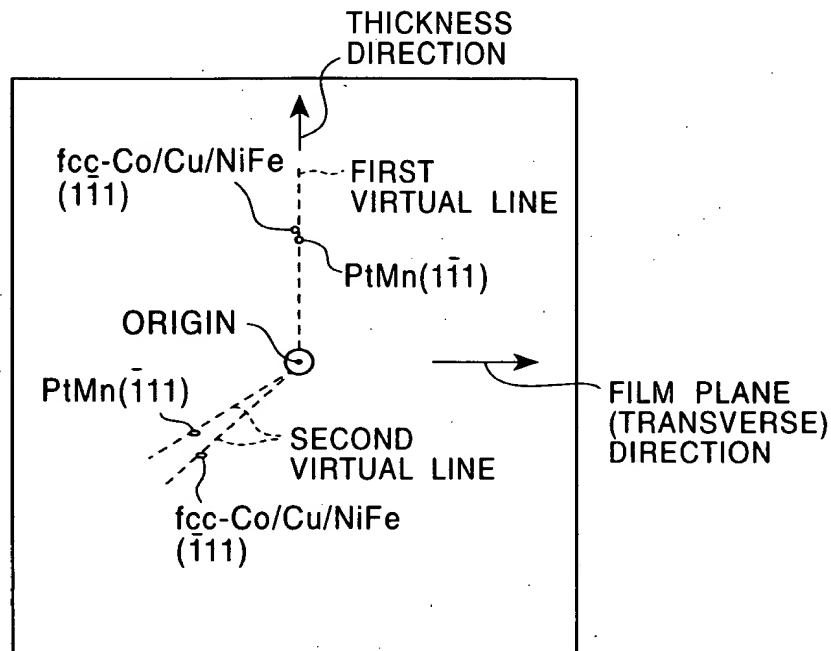
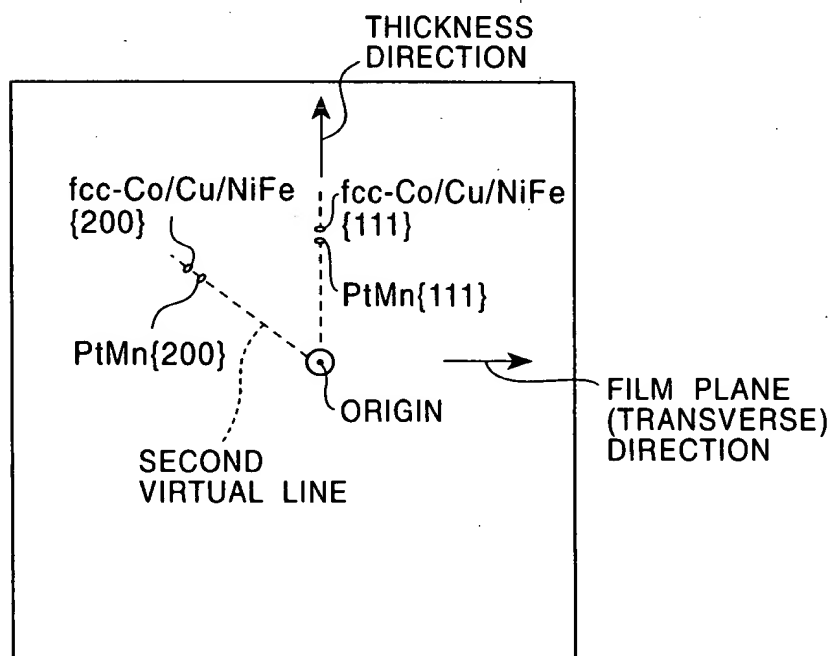


FIG. 19



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FIG. 20

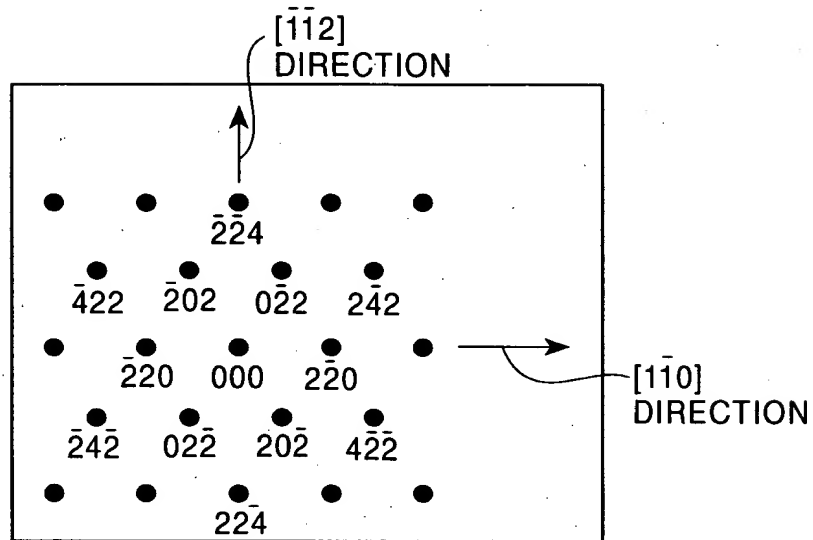
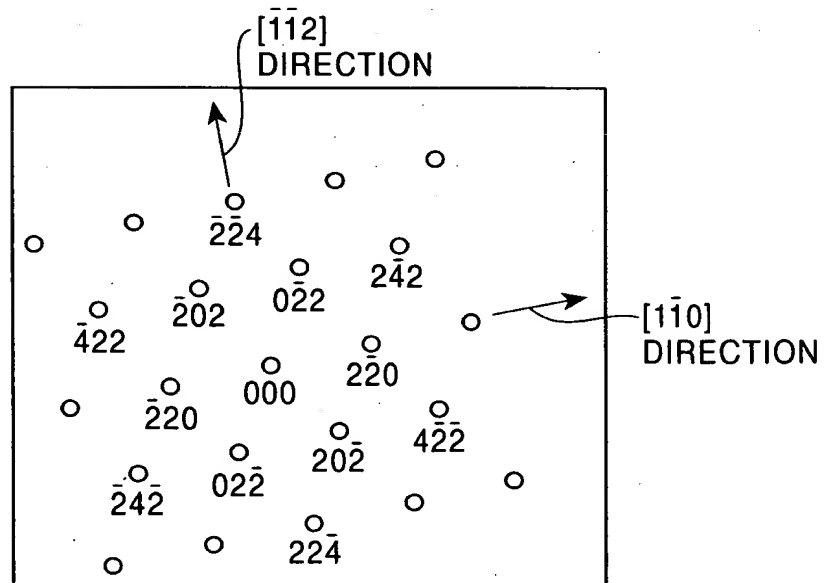


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FIG. 22

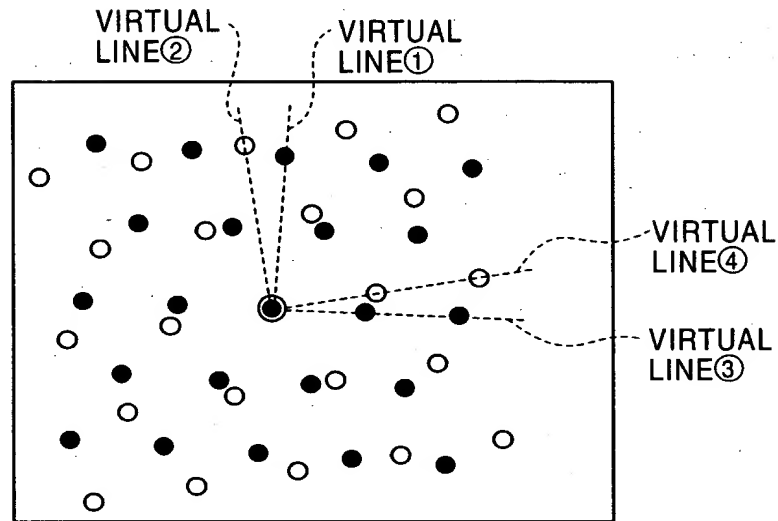
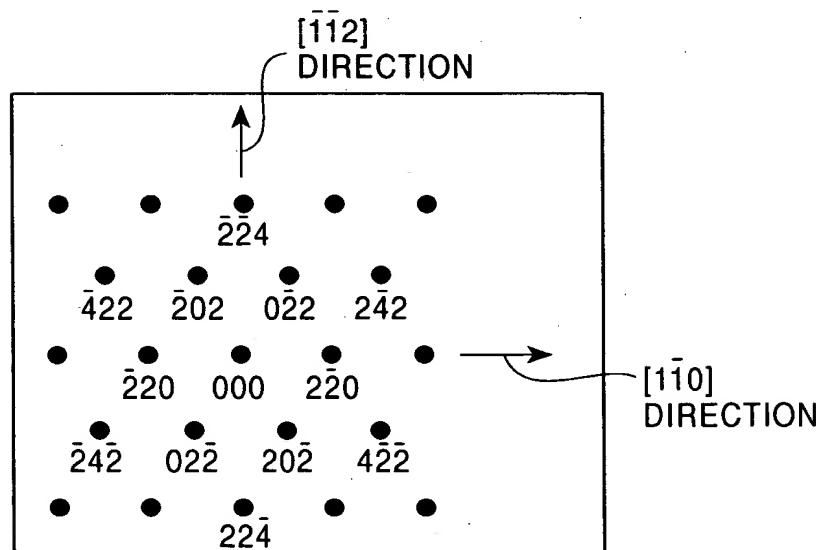


FIG. 23



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FIG. 24

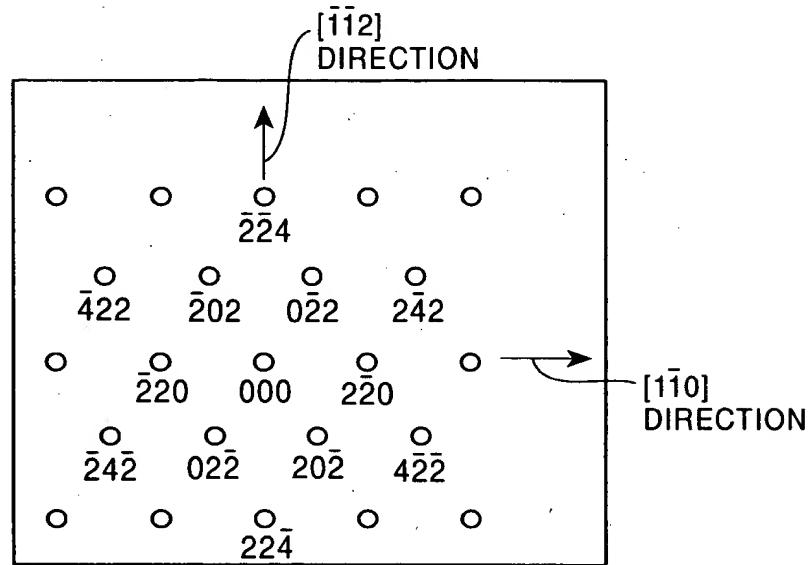


FIG. 25

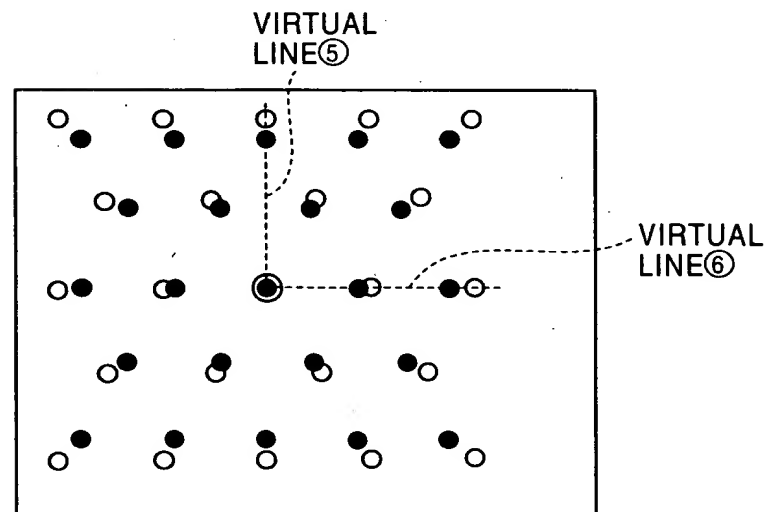


FIG. 26

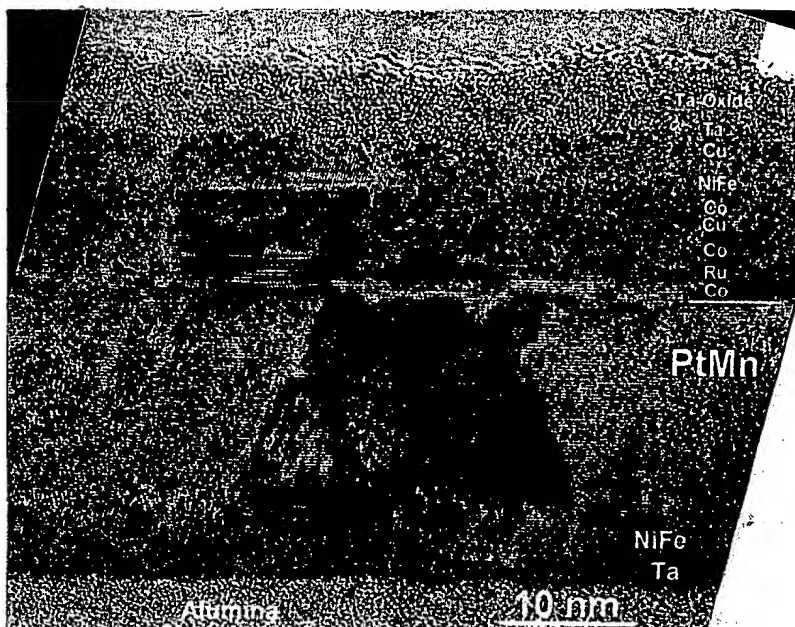
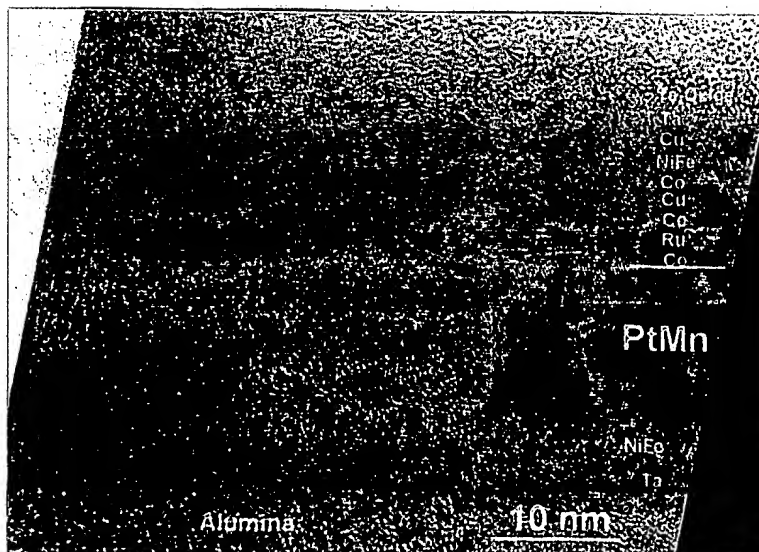


FIG. 27



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FIG. 28

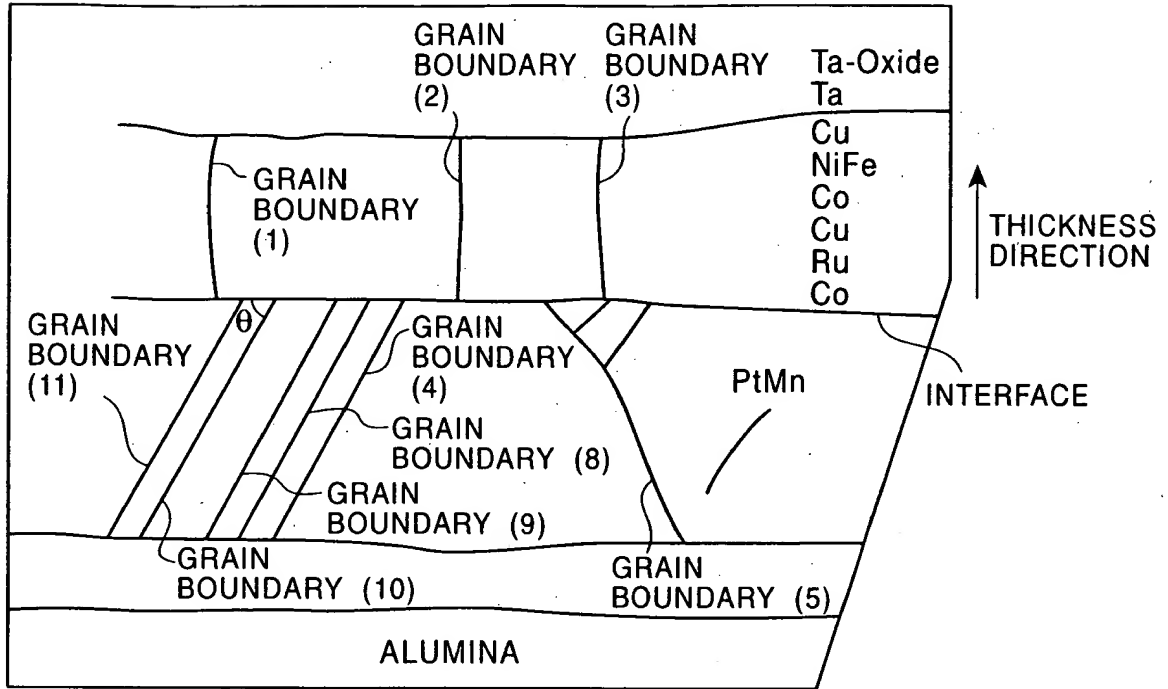
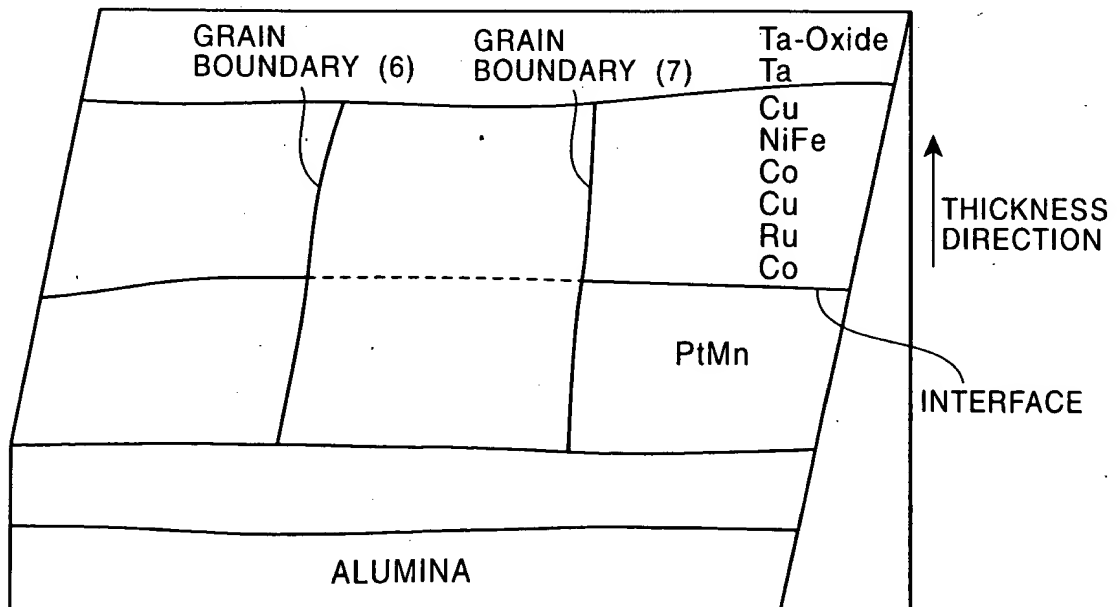
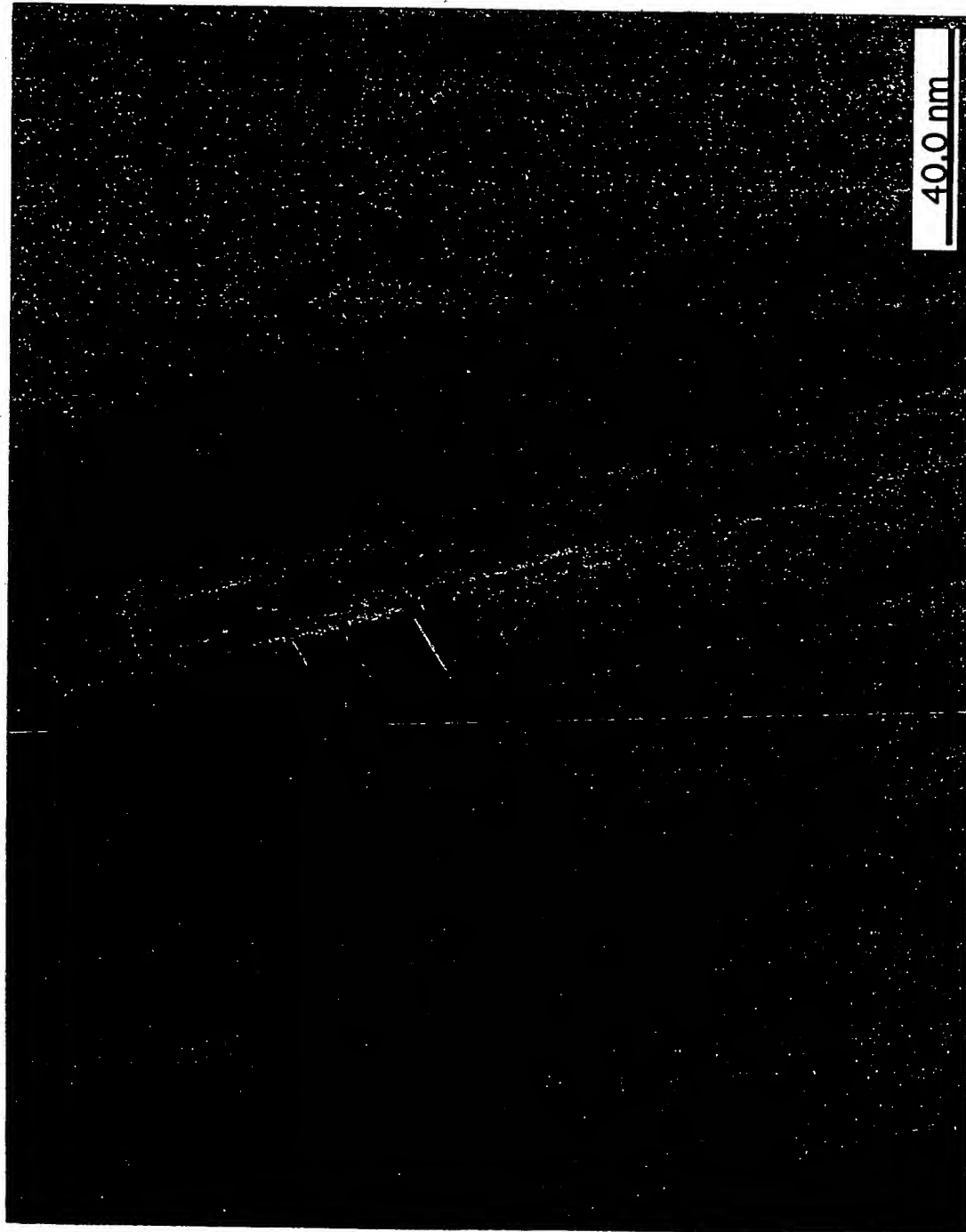


FIG. 29



TOP VIEW 2500000

FIG. 30



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FIG. 31

